IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Ying Zhou, et al.

Group Art Unit:

2812

Serial No.:

10/696,204

Examiner:

Filed:

October 29, 2003

For:

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Atty. Dkt. No.:

ITL.1024US (P16711)

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicant submits the references listed on the attached form PTO 1449 together with any required copies of such references.

This statement is being filed before the receipt of a first Office action on the merits. Please apply any charges or credits to Deposit Account 20-1504 (ITL.1024US).

Respectfully submitted,

April 2, 2004 Date:

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April 2, 2004 Date of Deposit: I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)			ATTY DOCKET NO. ITL.1027US (P16711) APPLICANT(S): YING ZHOU, ET AL. FILING DATE: GROUP ART UNIT:				
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